

PTO/SB/08A (04-03)

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Sheet 1 of 3

Complete if Known

Application Number	Not Yet Assigned <i>10/730,533</i>
Filing Date	12/08/2003
First Named Inventor	Chung-Hsing Chang
Art Unit	Not Yet Assigned <i>1756</i>
Examiner Name	Not Yet Assigned <i>Ruggles</i>
Attorney Docket Number	N1085-00018

U. S. PATENT DOCUMENTS

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FOREIGN PATENT DOCUMENTS

[illegible]

**Examiner
Signature**

John Ruggles

Date	Considered
11/1/78	11/1/78
11/2/78	11/2/78
11/3/78	11/3/78
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11/5/78	11/5/78
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11/27/78	11/27/78
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11/30/78	11/30/78

3/8/06

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		Examiner Name	Not Yet Assigned Ruggles
Sheet 2	of 3	Attorney Docket Number	N1085-00018

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
JSR	A	JOHN S. PETERSEN ET AL., "Development Of A Sub-100nm Integrated Imaging System Using Chromeless Phase-Shifting Imaging With Very High NA KrF Exposure And Off-Axis Illumination," 14 pages	
	B	FUNG CHEN ET AL., "Binary Halftone Chromeless PSM Technology For Lambda/4 Optical Lithography," Optical Microlithography XIV, Proceedings of SPIE Vol. 4346 (2001) Pages 515 - 533	
	C	KATHERINE DERBYSHIRE, "Next-Generation Lithography: Beyond 100 NM, In The NGL Race, Only Extreme Ultraviolet And Projection Beam Technologies Are Still Contenders" at http://www.semi.org/web/wmagazine.nsf/4f55b97743c2d02e882565bf006c245... 10/11/2003, 8 pages	
	D	DOUGLAS VAN DEN BROEKE, "Transferring Phase-Shifting Mask Technology Into Mainstream Manufacturing," at http://www.semiconductorfabtech.com/features/lithography/articles/body5.225... 10/11/2002; 8 pages	
	E	IBM, LARS W. LIEBMANN, "Layout Impact Of Resolution Enhancement Techniques: Impediment Or Opportunity?", Pages 110-117	
	F	LONG QUE ET AL., "Chromeless Phase-Shift Technology: The Physical Mechanism Of The Dark Area Produced by Phase-Compensation And Its Application," SPIE Vol. 1927	
JSR		Optical/Laser Microlithography VI (1993), Pages 709 - 714.	

Examiner Signature	<i>John Ruggles</i>	Date Considered	3/8/06
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Sheet 2

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3

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	D	DOUGLAS VAN DEN BROEKE, "Transferring Phase-Shifting Mask Technology Into Mainstream Manufacturing," at http://www.semiconductorfabtech.com/features/lithography/articles/body5.225... 10/11/2002, 8 pages	
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Examiner Signature	<i>John Ruggles</i>	Date Considered	3/8/06
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Sheet 3

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12/08/2003

First Named Inventor

Chung-Hsing Chang

Art Unit

Not Yet Assigned	1756
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Examiner Name

~~Not Yet Assigned~~ Ruggles

Attorney Docket Number

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NON PATENT LITERATURE DOCUMENTS

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**Examiner
Signature**

John Huggins

Date Considered

3/8/06

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